

Notice of References Cited	Application/Control No. 10/662,162	Applicant(s)/Patent Under Reexamination HEFFNER ET AL.	
	Examiner B. Chen	Art Unit 1792	Page 1 of 1

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*	B	US-6,884,290	04-2005	Swain et al.	117/68
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NON-PATENT DOCUMENTS

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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